

LARGE ACOUSTOELECTRIC EFFECT IN WAFER BONDED INDIUM GALLIUM ARSENIDE / LITHIUM NIOBATE HETEROSTRUCTURE

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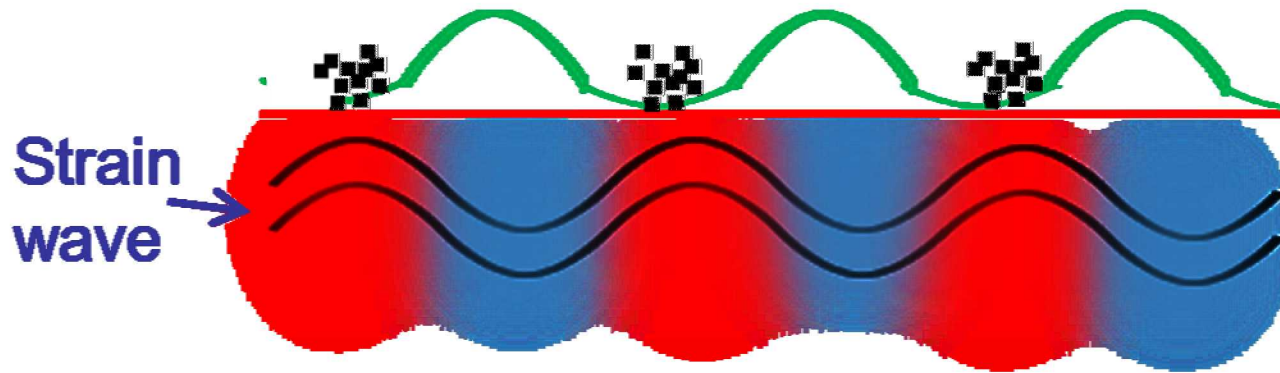


Outline

- ☐ Introduction
- ☐ Fabrication
- ☐ Demonstration of large gain
 - Rayleigh Wave
 - Leaky SAW – Terminal Gain
- ☐ Power Optimization
- ☐ Conclude

Acoustoelectric (AE) Interaction

- Carriers and surface acoustic wave (SAW) interact through a mutual quasi-static electric potential due to piezoelectricity



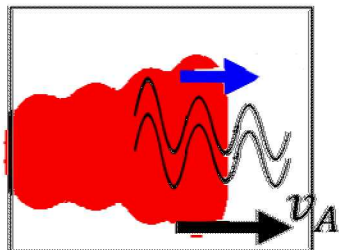
Material stack

Semi-Conductor
Piezo-electric

to attenuation/gain

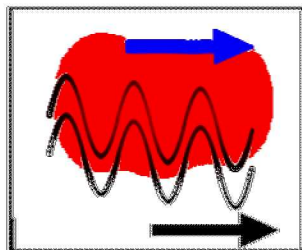
Attenuation

$$v_e < v_A$$



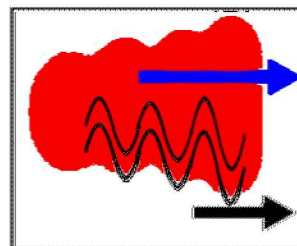
No loss

$$v_e = v_A$$



Amplification

$$v_e > v_A$$



$$P_{out} = P_{in} e^{\Gamma L}$$

$$\Gamma = K^2 \frac{\pi}{\lambda} \times \frac{x}{1 + (x)^2}$$

$$x = \left(\frac{v_A - \mu E}{v_A} \right) \frac{\sigma_m}{\sigma}$$

$$\sigma_m = (\epsilon_P + \epsilon_0) v_A$$

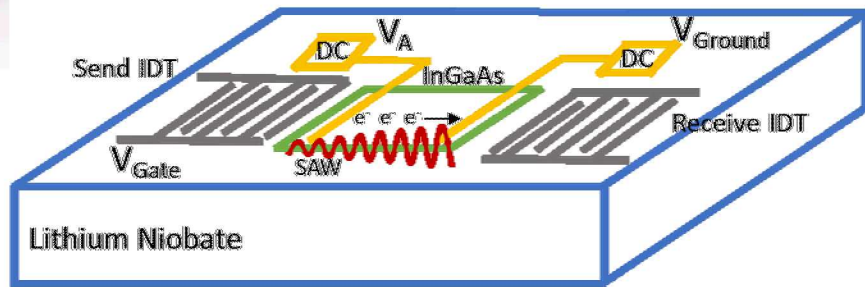
Sheet conductivity

$$: \sigma = en\mu \times d$$

Electro mechanic coupling: K_T^2

Gain Dependence on Electric Field

□ Gain in a delay line through the AE effect



$$\Gamma = K^2 \frac{\pi}{\lambda} \times \frac{x}{1 + (x)^2} \quad x = \left(\frac{v_A - \mu E}{v_A} \right) \frac{\sigma_m}{\sigma}$$

$$P_{out} = P_{in} e^{\Gamma L}$$

】Max Gain Dependence and Voltage Requirements

$$Gain_{max} = \frac{1}{4} K_{eff}^2 k_0 \times 4.3 \times 10^{-3} \quad [db/cm]$$

$$E_{max} = \frac{c_{sound}}{\mu} + \frac{q \times \rho_{carriers} \times d_{SemiConductor}}{\epsilon_{eff}}$$

Match speed
of sound

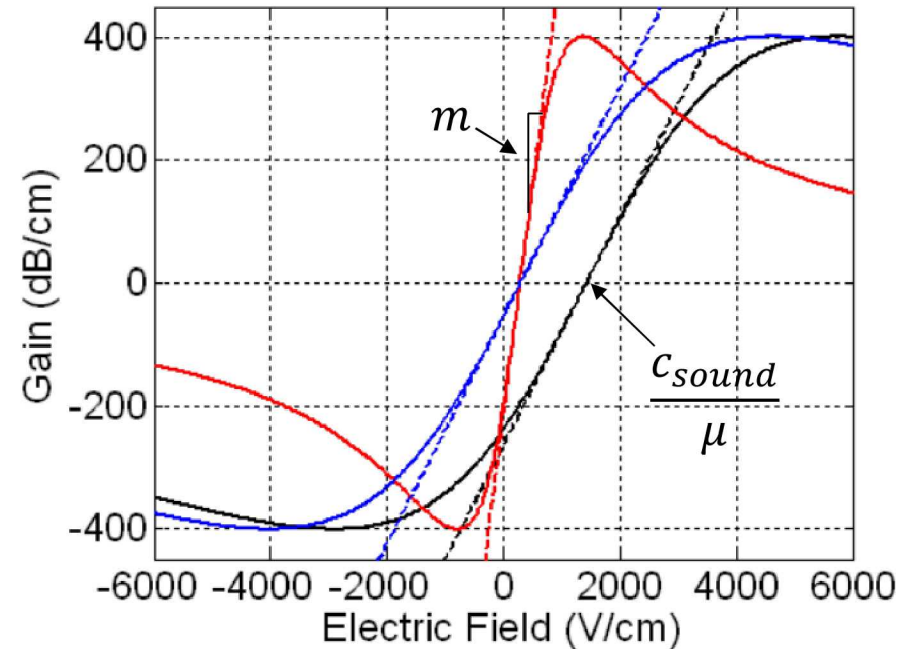
Extra field to get to
max gain

$$V_{Tot} = V_{0dB} + \Delta V_{dB} \quad \Delta V_{dB} = \frac{dB_T}{m},$$

Low voltage {

- High mobility
- Low Doping
- Mode with large K_T^2

→ Epitaxial InGaAs on Lithium Niobate

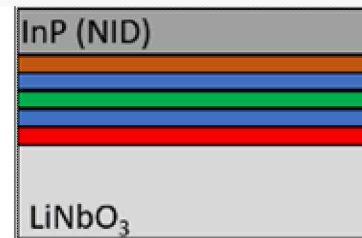
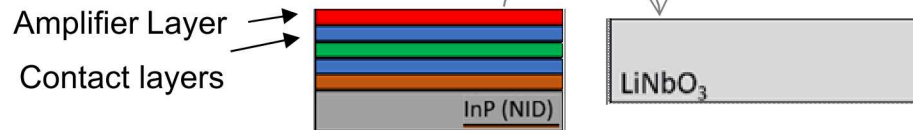


$$m = 0.0869 \times K_r^2 \frac{\pi}{\lambda} \left(\frac{\epsilon_P + \epsilon_0}{d \times e \times n} \right)$$

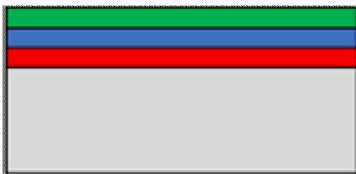
Fabrication Flow

❑ Process flow utilizing a III-V epitaxial semiconductor stack bonded to a Y-cut LiNbO₃ wafer

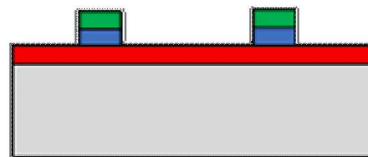
1. Bond InP substrate with epitaxial layers to LiNbO₃



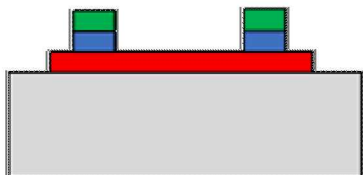
2. Wet etch removal of InP buffer, InGaAs, and InP etch stop layer



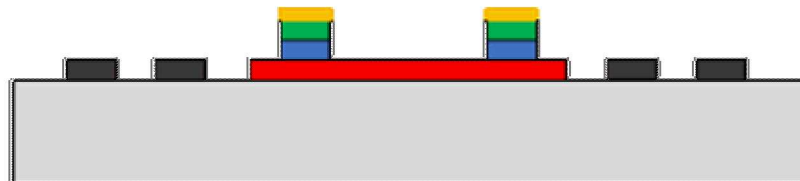
3. Pattern and etch InGaAs/InP contact layers



5. Pattern and etch InGaAs amplifiers

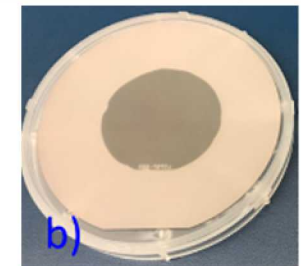
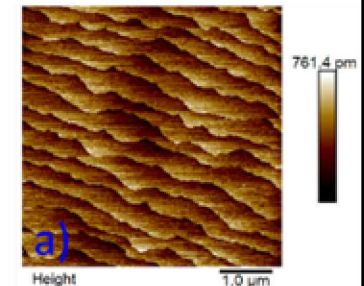


6. Metal patterning, deposition, and liftoff for SAW transducers and semiconductor contacts

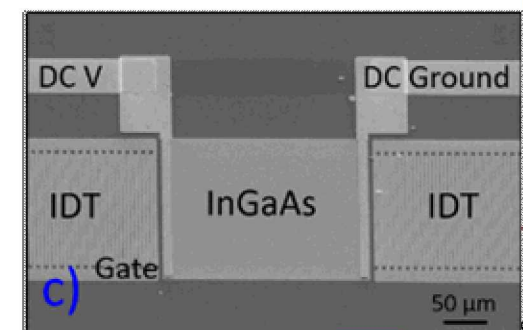


■ InGaAs (NID) ■ InP (n+, 1e18 cm⁻³) ■ InGaAs (n+, 2e19 cm⁻³) ■ Al ■ Au/Ag
■ InGaAs (n, 4e15 cm⁻³) ■ LiNbO₃ ■ InP (NID)

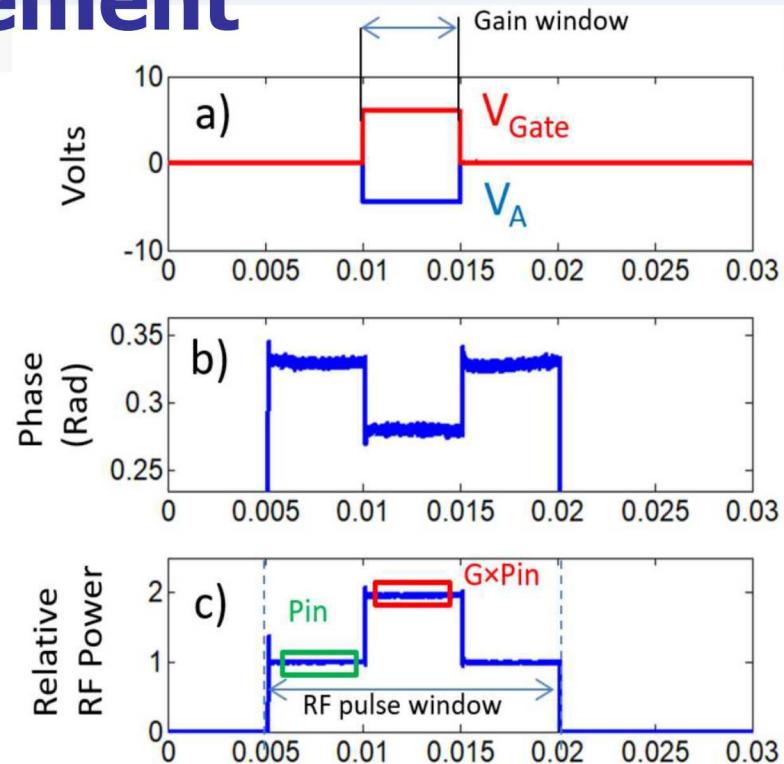
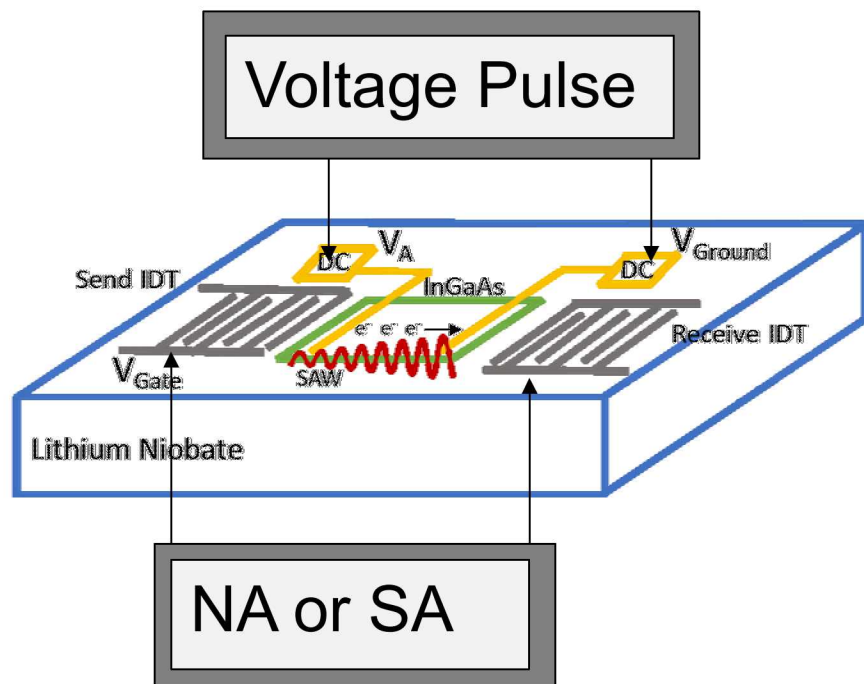
Flatness and bonding completeness



SEM of Device



Device Characterization and Measurement



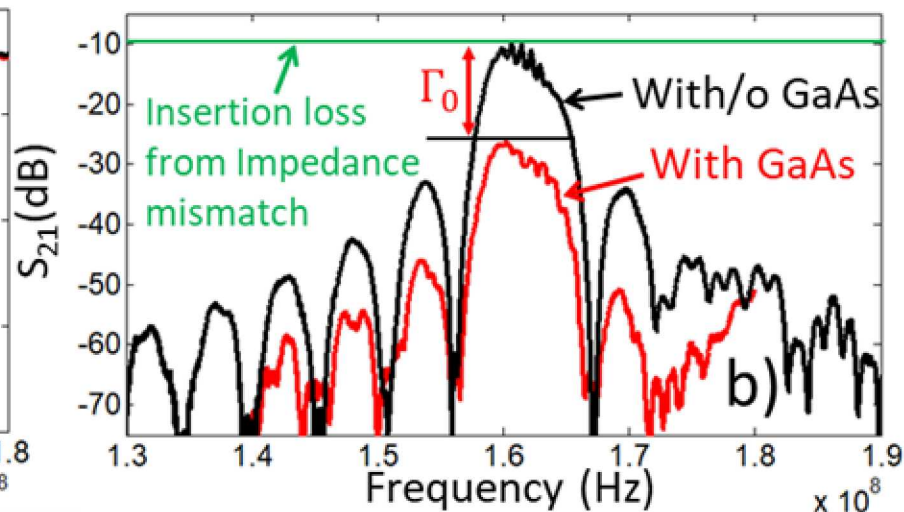
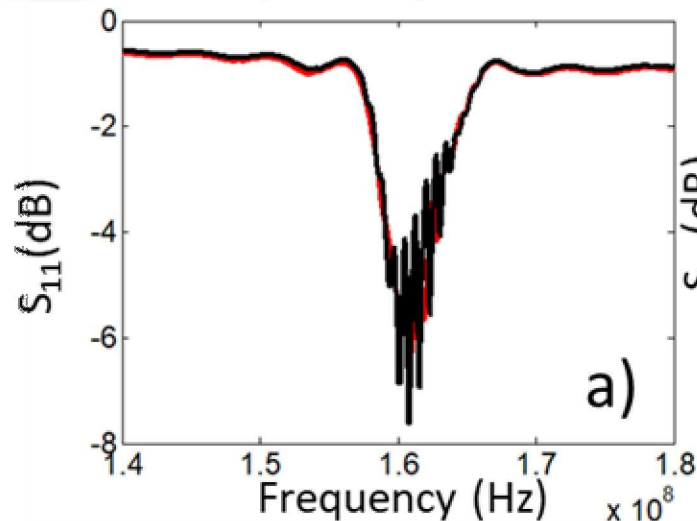
- RF and electrical resistance measurements set system parameters.

$$\mu \quad n_d \quad \sigma = en\mu \times d \quad \lambda \quad K_T^2 \quad IL \quad v_A \quad \sigma_m$$

- Impedance matching
- Pulsed Gain
- Electrical and capacitive measurements.

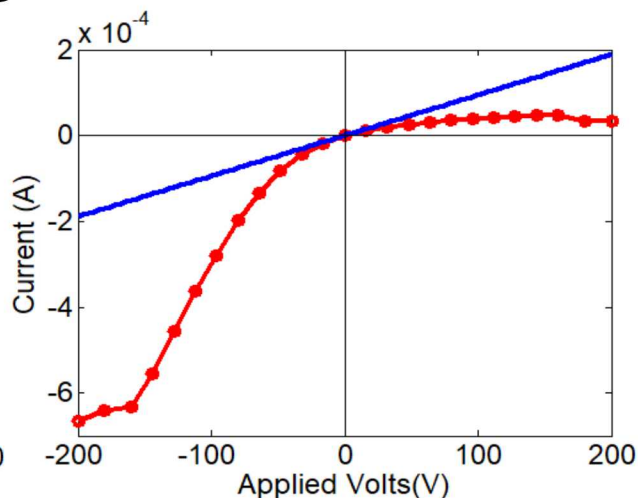
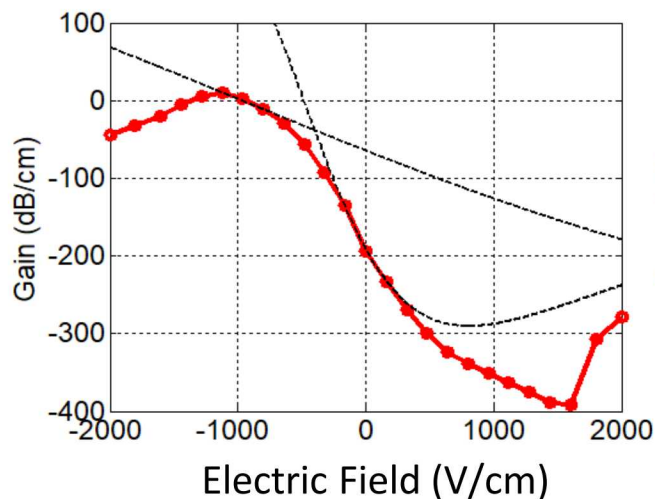
Device Design for Y-cut Z-Propagating

- Impedance matching in Send Receive Device: $L=1\text{mm}$, $N_{\text{fingers}}=60$, pitch= $10.5\mu\text{m}$, Aperture= $210\mu\text{m}$

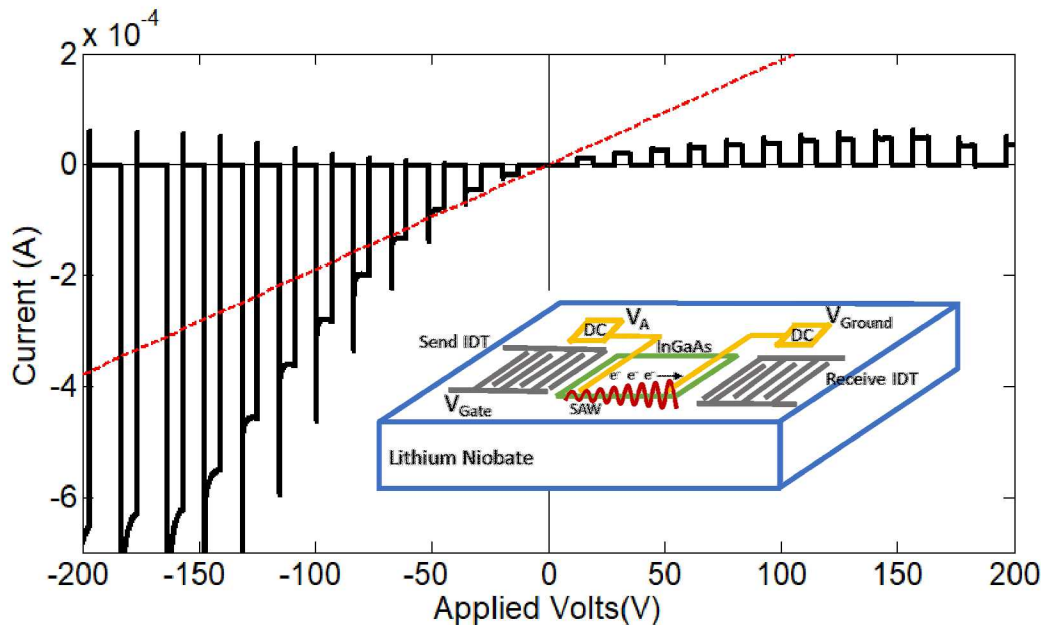
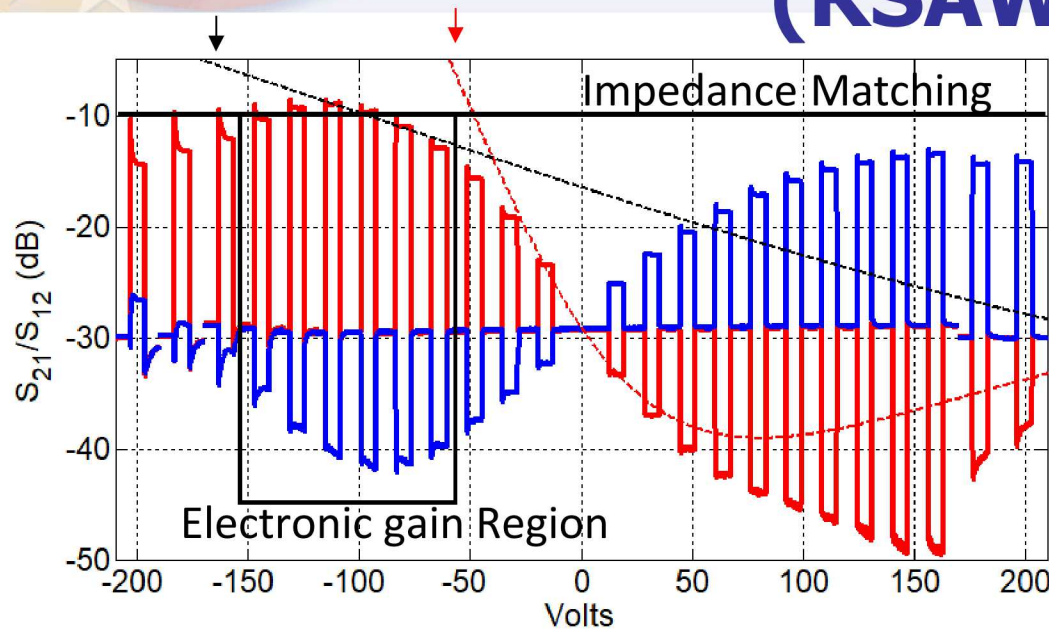


Zero-field attenuation: $\Gamma_0 = -214\text{dB/cm}$

- Measured gain and IV curve



Electronic Gain With Rayleigh SAW (RSAW)



□ Electronic gain achieved

→ Zero field attenuation to extrapolate gain predicts large gain

$$n_d = 4 \times 10^{15} \text{ cm}^{-3}$$

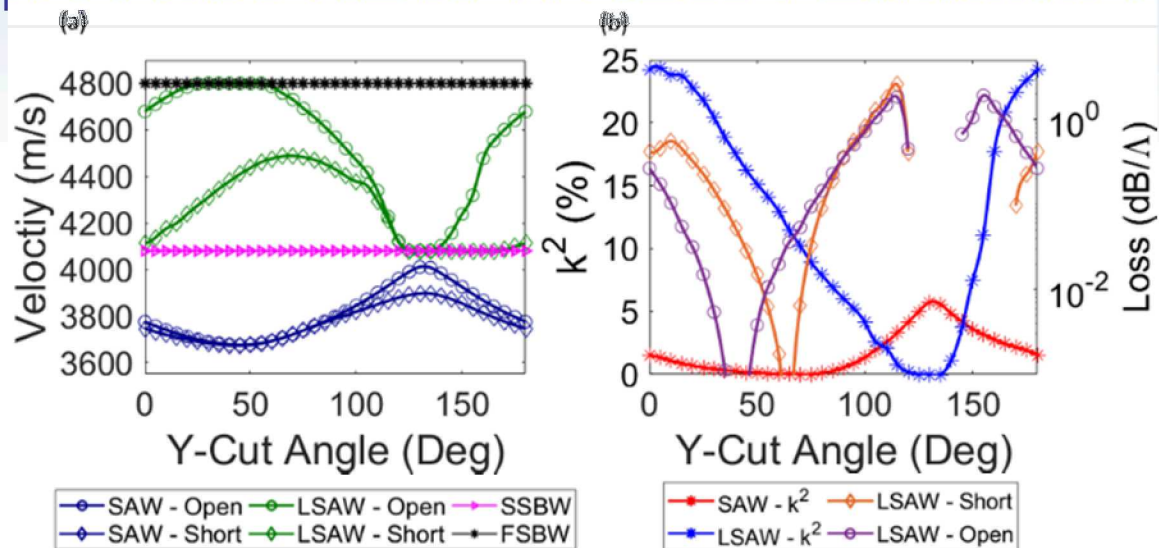
$$\mu = 702 \text{ cm}^2/\text{V}$$

→ Used measured conductivity with half mobility to rationalize loss of gain

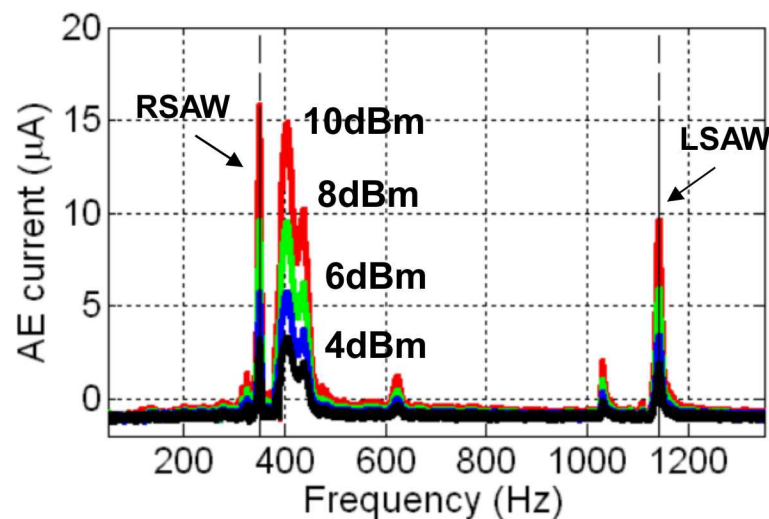
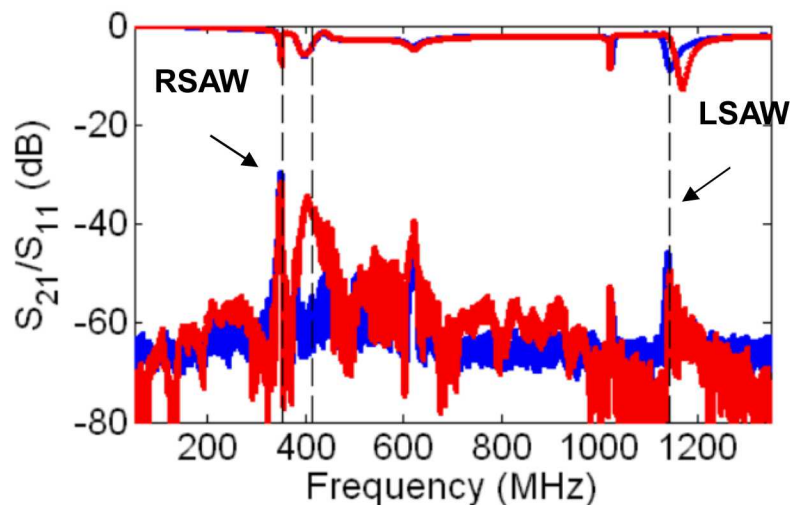
Gain may be limited due to pinch off effects, band bending or thermal effects

Y-Cut X-propagation Leaky SAW (LSAW) Amplifier

- ❑ LSAW has large K_T^2
 - 0° : large K_T^2 but large loss.
 - 41° or 64° cuts
- ❑ AE gain must be large to counteract propagation loss

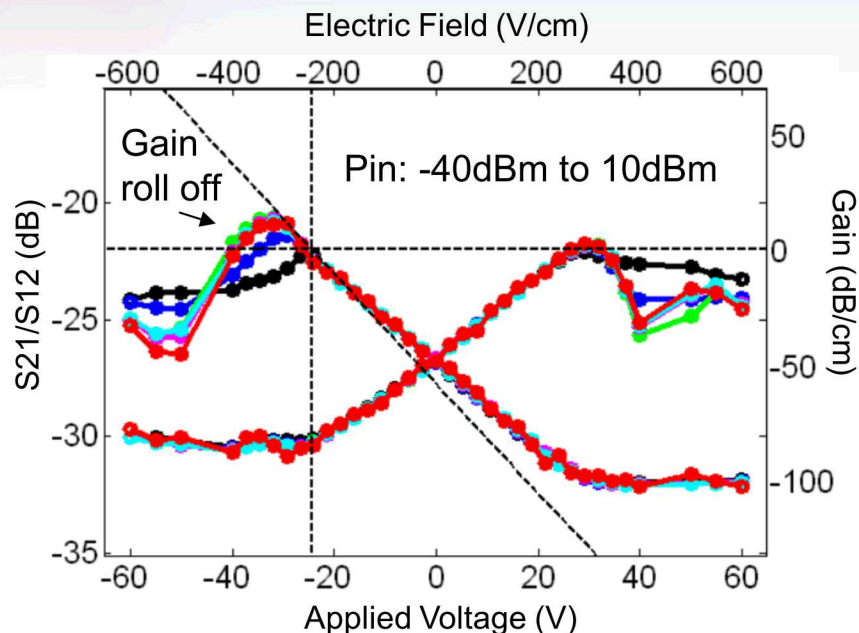


- ❑ Device Design: Amplifier: Length=1mm, Width=429μm,
Transducer: $N_{\text{fingers}}=90$, pitch=50μm, Aperture=210μm

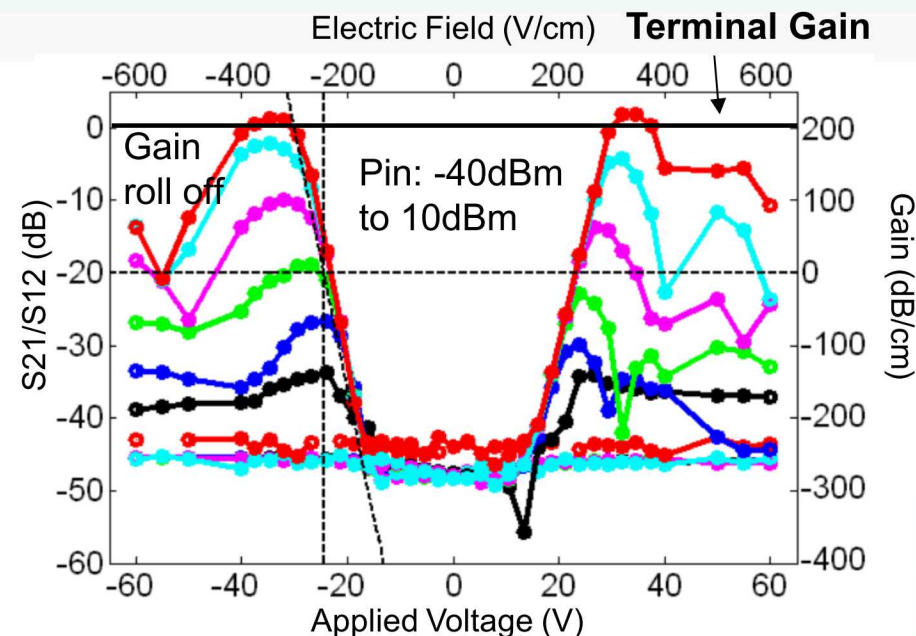


Comparison Between SAW and LSAW

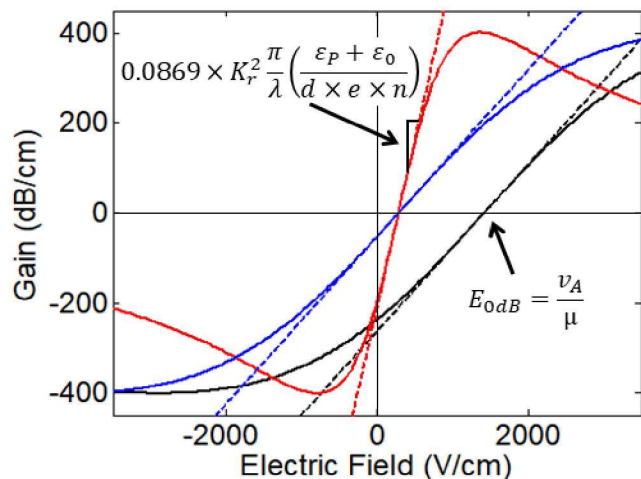
RSAW



LSAW



□ Gain Comparison



- dB=0 position is fixed by mobility
- Slope increase by a factor of 5

$$K_{LSAW}^2 \text{ nearly } 5 \times K_{RSAW}^2$$

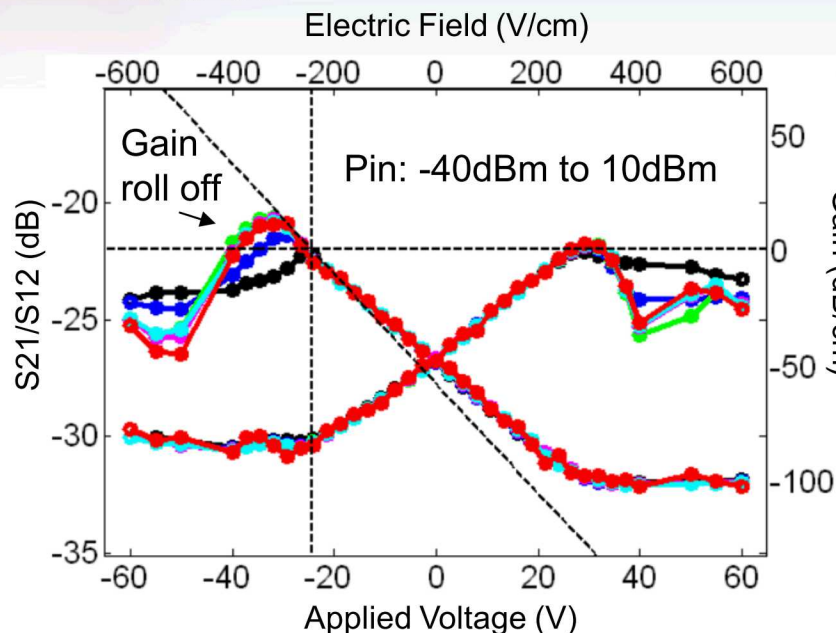
$$n_d = 20e15cm^{-3}$$

$$\mu = 1700cm^2/V$$

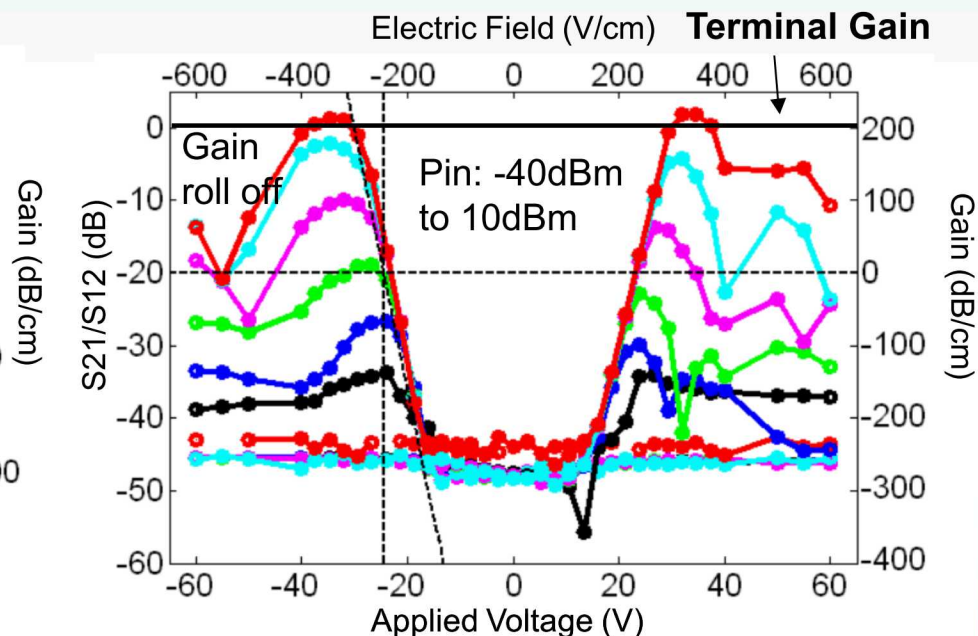
- Terminal gain of 3dB

Comparison Between SAW and LSAW

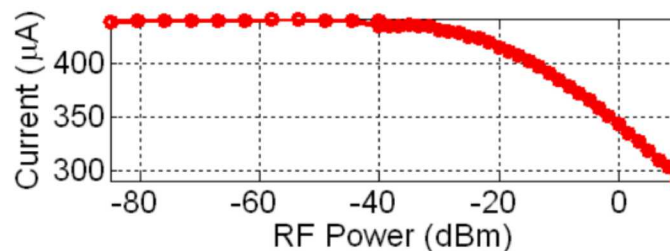
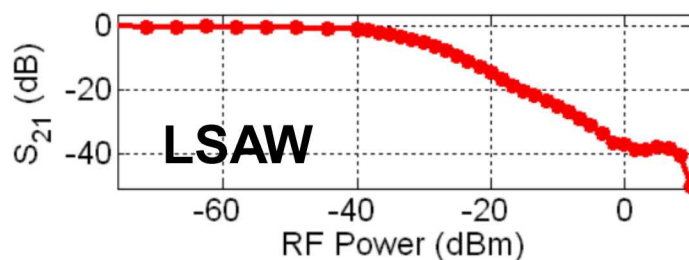
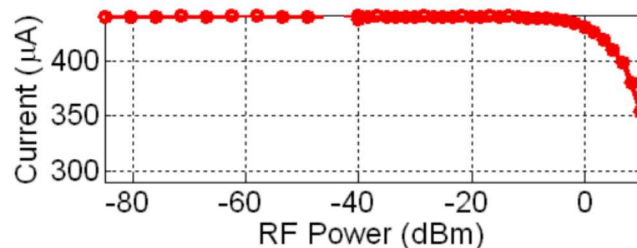
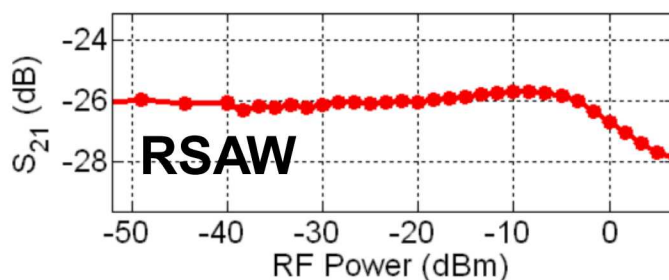
RSAW



LSAW



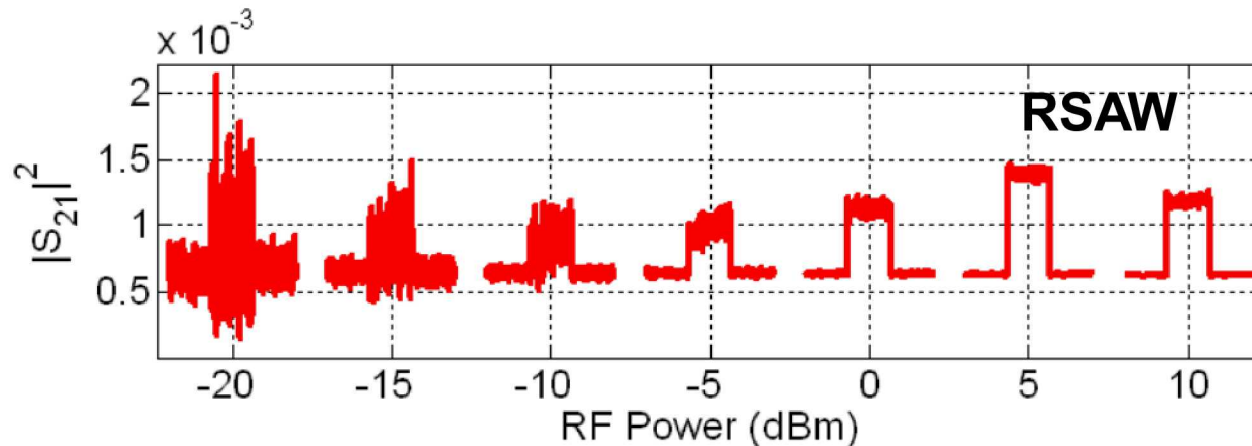
Gain and Current Saturation



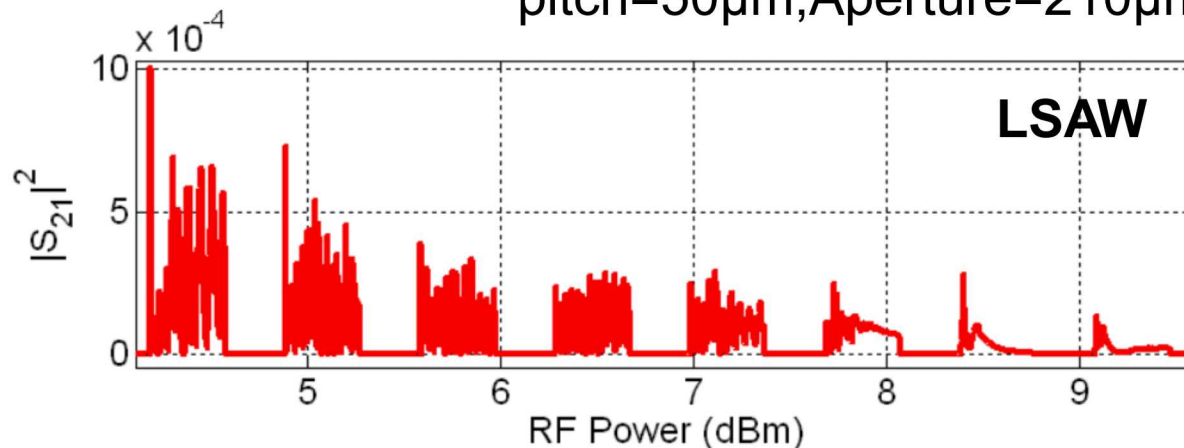
→ LSAW saturates at lower power and larger current impedance

Noise Competition In Gain Roll Off Region

- Gain in a short distance is sufficiently large that noise saturation effects come into play Noise saturation

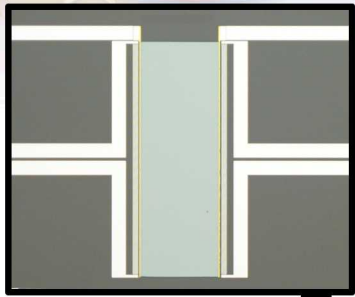


- Similar Device with: Amplifier: Length=1mm, Width=1 μ m,
Transducer: $N_{\text{fingers}}=90$,
pitch=50 μ m, Aperture=210 μ m

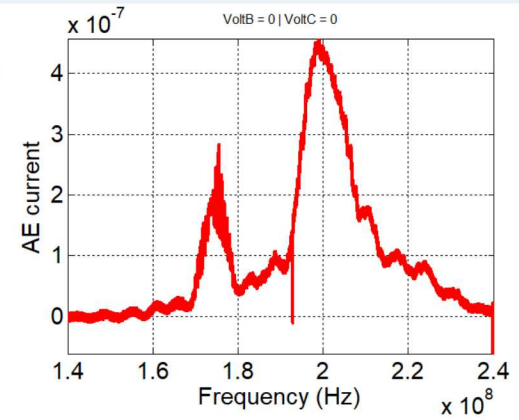
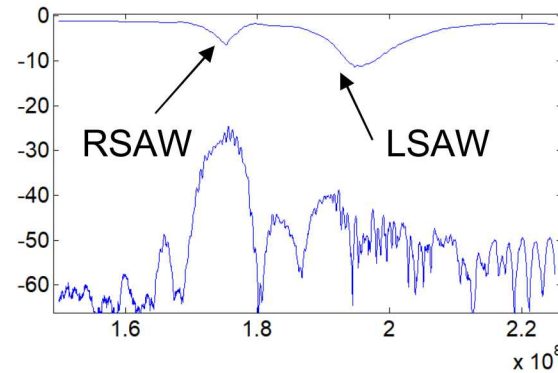


Best Performer LSAW

Confirm KT2 by measuring AE current



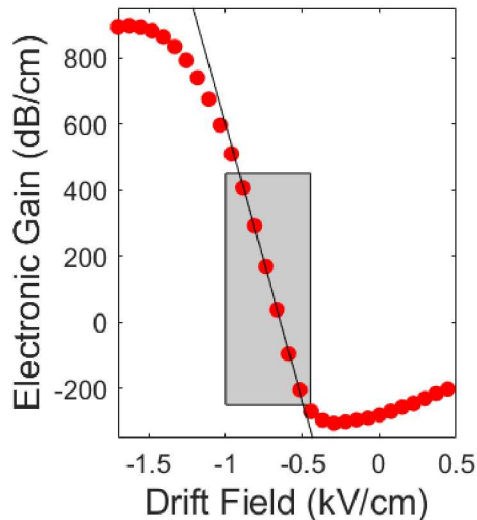
250 μm



We achieved large gain using LSAW:

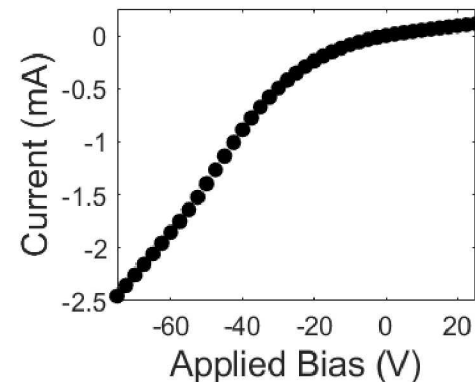
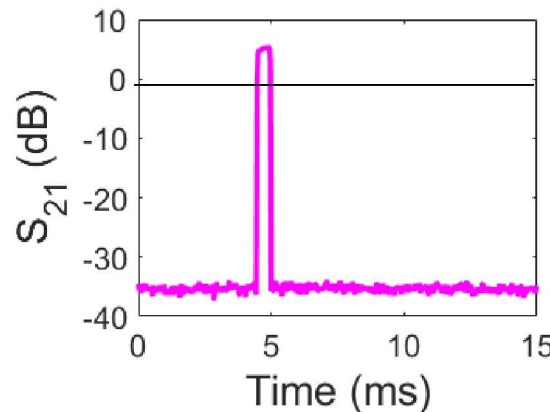
→ 5dB terminal, 30dB electronic with 90mW power

L. Hackett, et. Al. "High-Gain Leaky Surface Acoustic Wave Amplifier in Epitaxial InGaAs on Lithium Niobate Heterostructure". APL 2019



$$n_d = 5.2e15\text{cm}^{-3}$$

$$\mu = 732\text{cm}^2/\text{V}$$



→ 41° or 64° cuts

→ Use Single-Phase unidirectional transducer design (SPUDT)

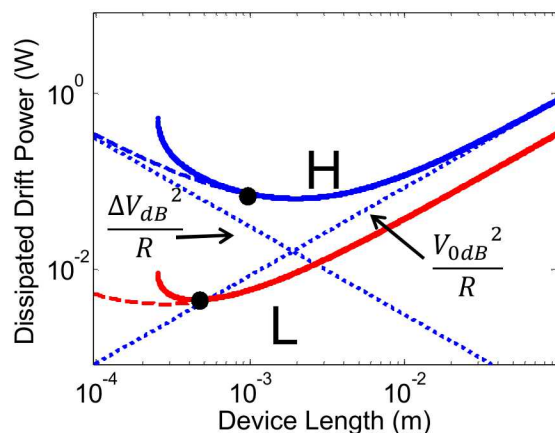
Power Optimization

- Trade off between long devices needing more power for 0dB and short devices burning up power with a fixed ΔV_{dB}

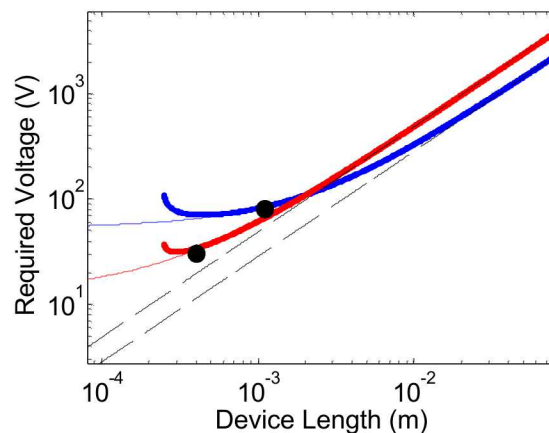
H $n_d = 20e15cm^{-3}$
 $\mu = 1700cm^2/V$

L $n_d = 5.2e15cm^{-3}$
 $\mu = 732cm^2/V$

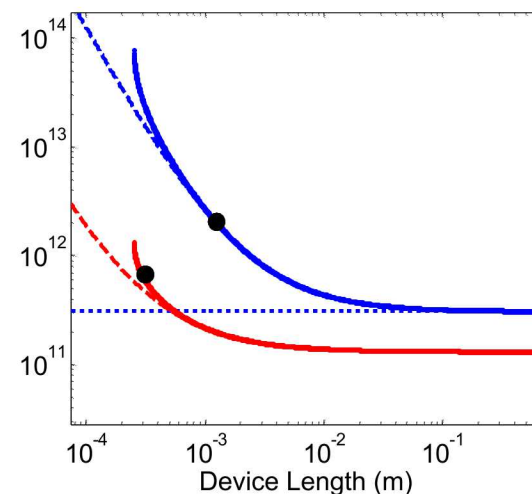
- Voltage required for 10 dB of gain



- Total Power dissipated



- Power Per unit volume



- Device Lengths are near optimal values
- Optimal dissipation is not the only consideration
 - Longer devices need more voltage
 - But dissipate less power per unit volume
 - Noise competition

Conclusion

- Given overview of gain via AE interaction
- Proposed a scalable fabrication method based on wafer-scale bonding of InGaAs and Lithium Niobate
- Demonstration of strong gain interaction
 - Terminal gain with LSAW
- Next step steps:
 - 41° or 64° cuts
 - SPUDT
 - CW operation

